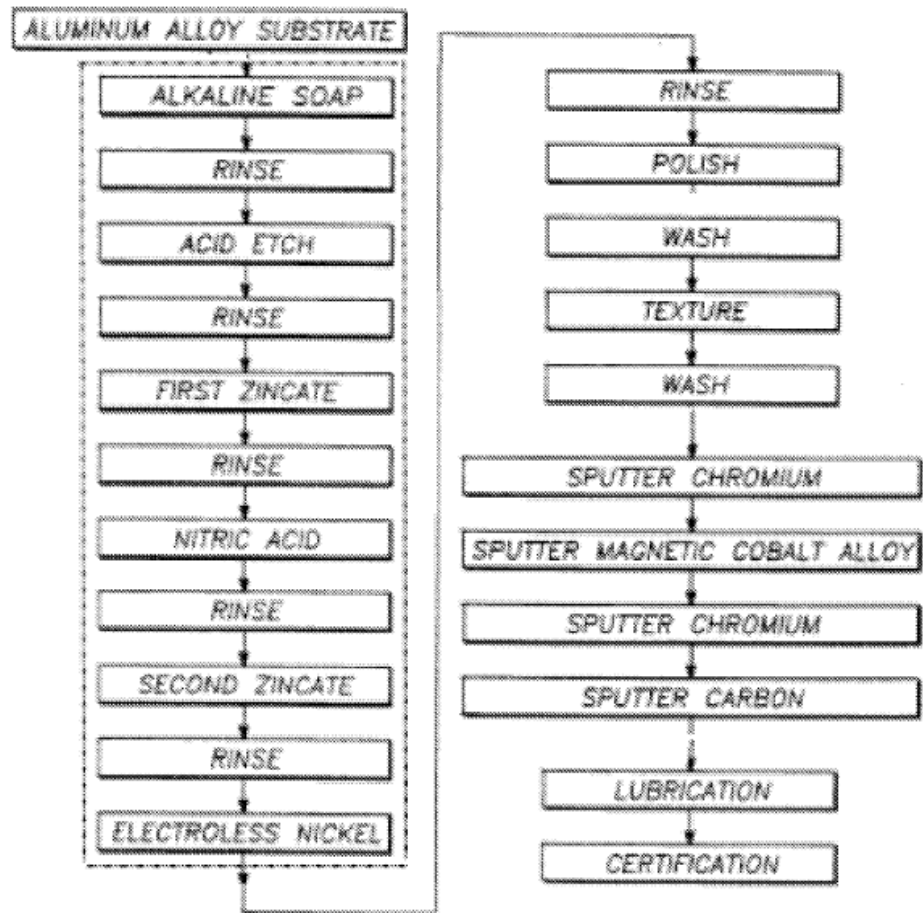


FIGURES

PRIOR ART

Fig. 1. Flow Chart of Rigid Memory Disk Production.

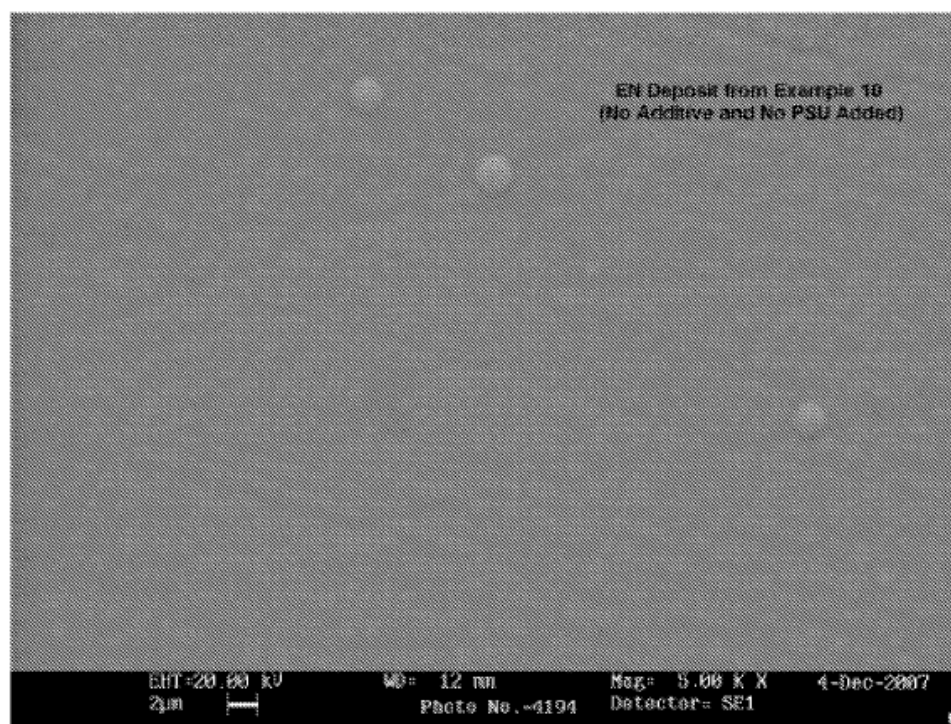


Fig. 2. Depiction of EN Coating on Al Substrate Plated from a Non-Polysulfone-Contaminated, High-P EN Bath. The Bath did not contain any Additive.

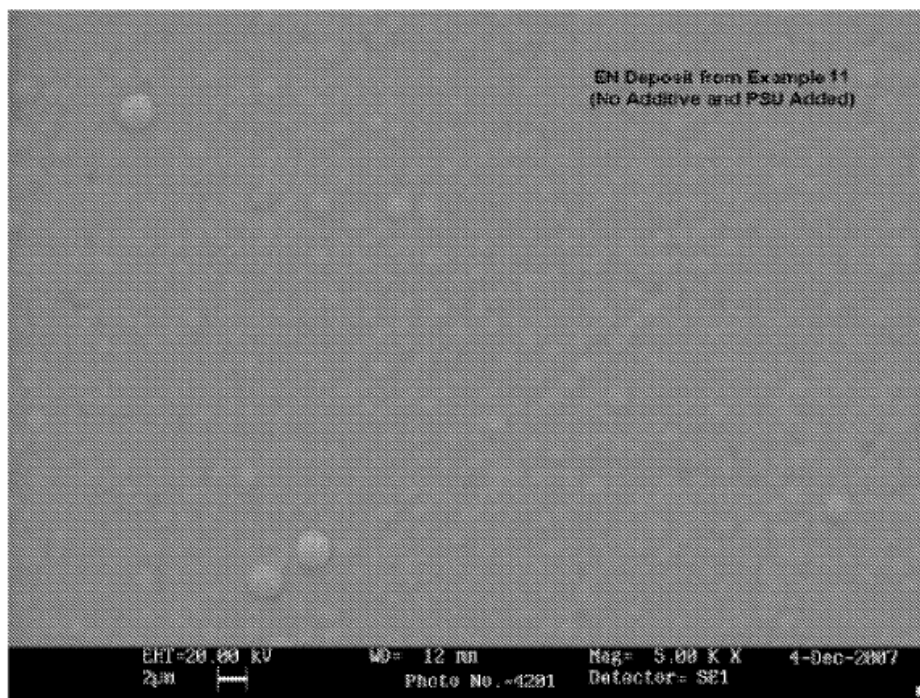


Fig. 3. Depiction of EN Coating on Al Substrate Plated from a High-P EN Bath that was Intentionally Contaminated with 200 nm Plastic Particles. The Bath did not contain any Additive.

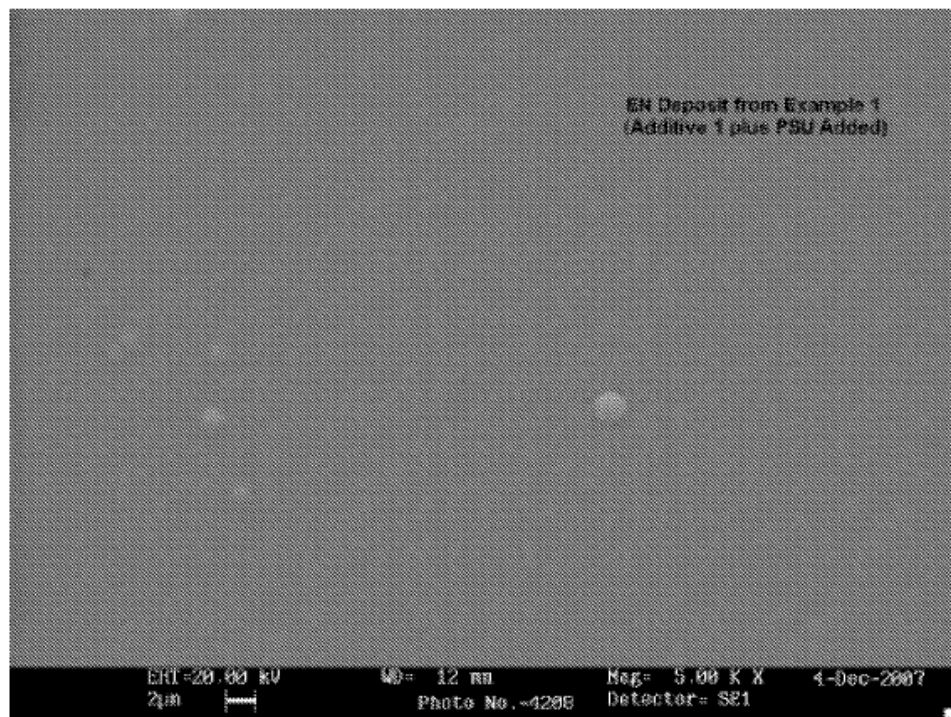


Fig. 4. Depiction of EN Coating on Al Substrate Plated from a High-P EN Bath that was Intentionally Contaminated with 200 nm Plastic Particles, the Bath containing the Additive of the Present Invention.

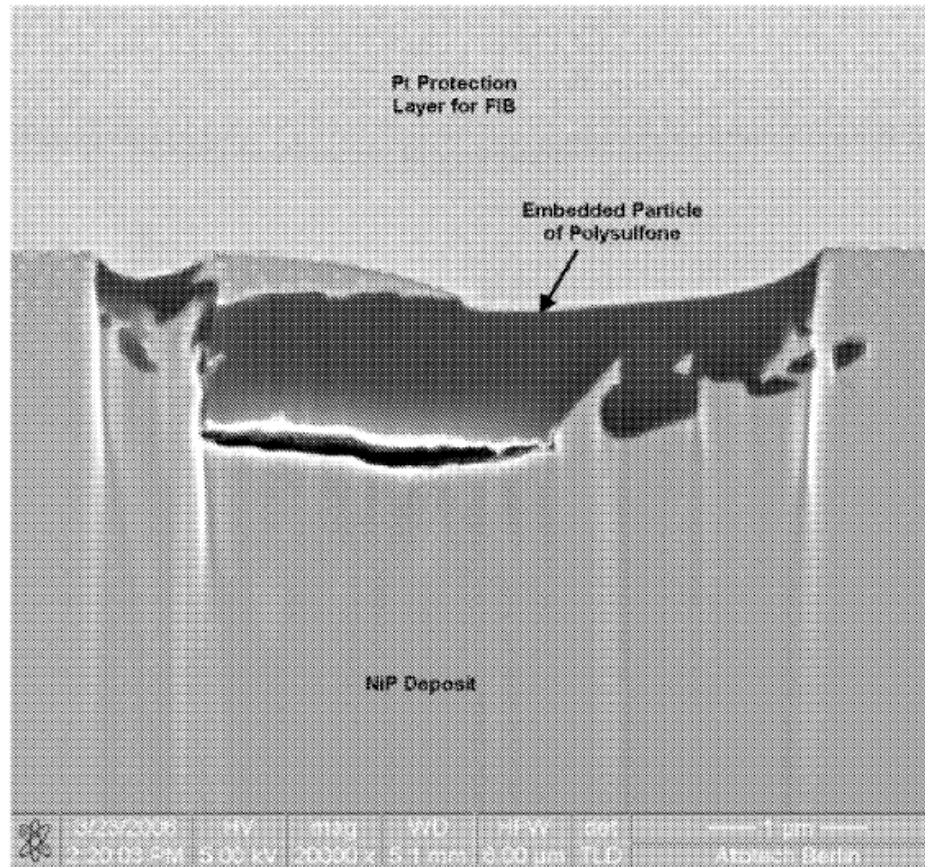


Fig. 5. Polysulfone Particle Embedded in an Electroless Nickel Coating.

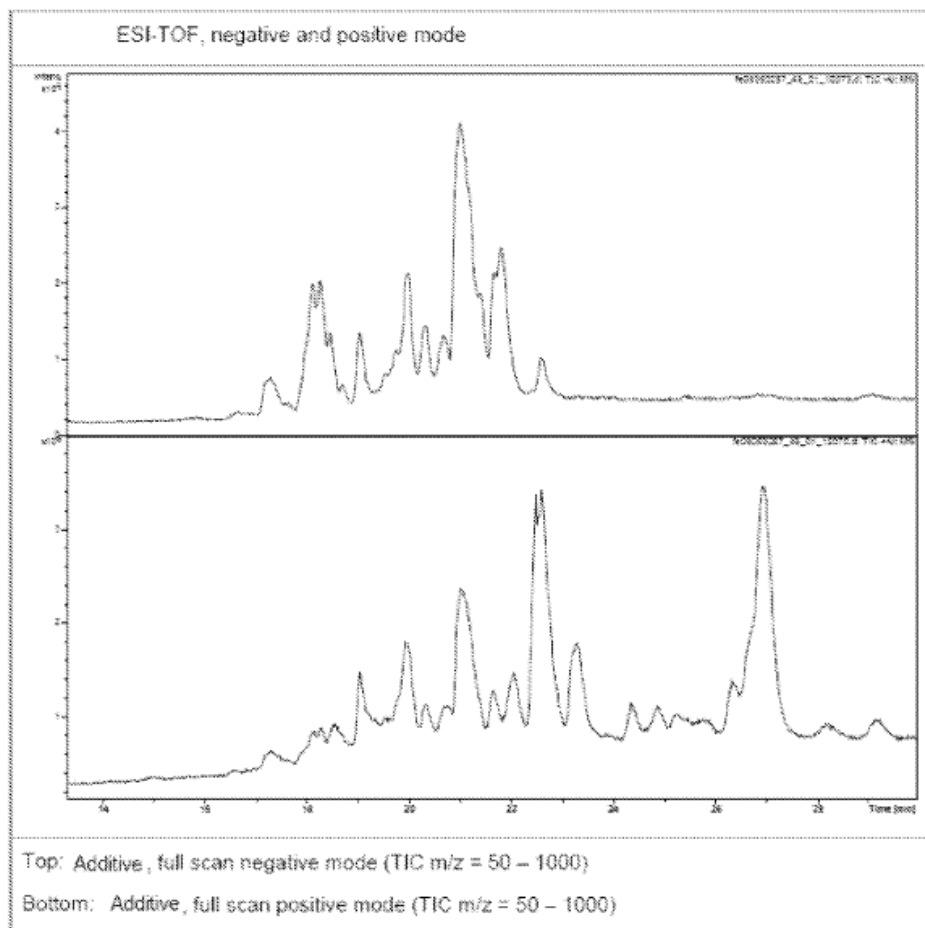


Fig. 6. Mixture Separation of the Sulfated, Fatty Acid Ester (Additive) by Chromatography Showing Retention Time on the Column in Minutes.

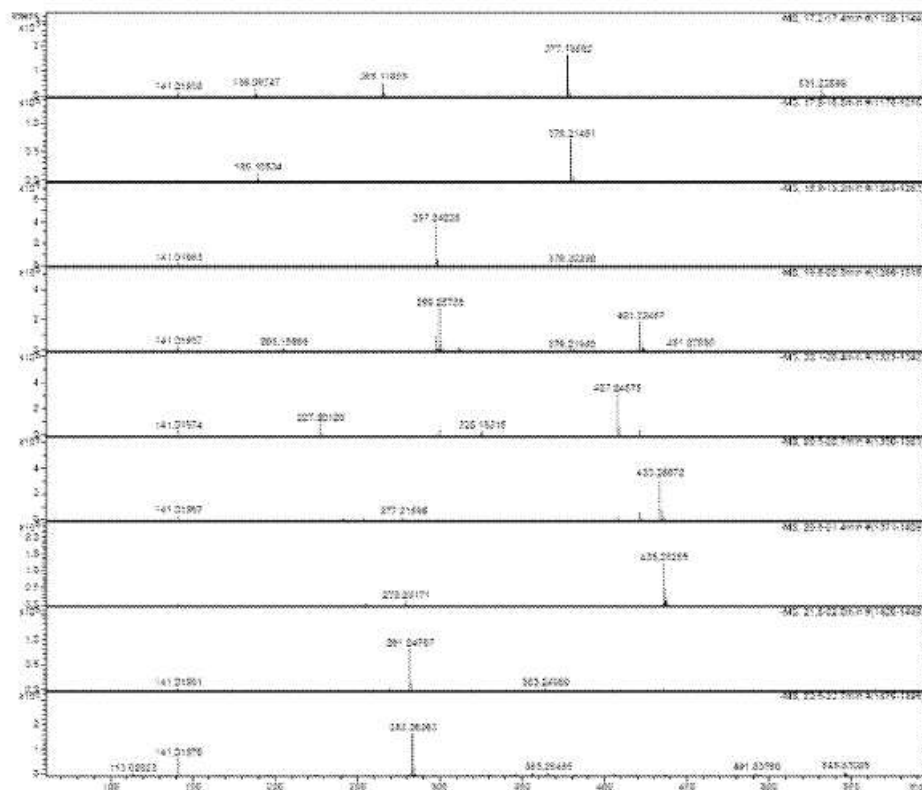


Fig. 7. Ion Chromatography (time-of-flight) Mass Spectrometry (IC-MS) spectrum of certain fractions contained in additive mixture.

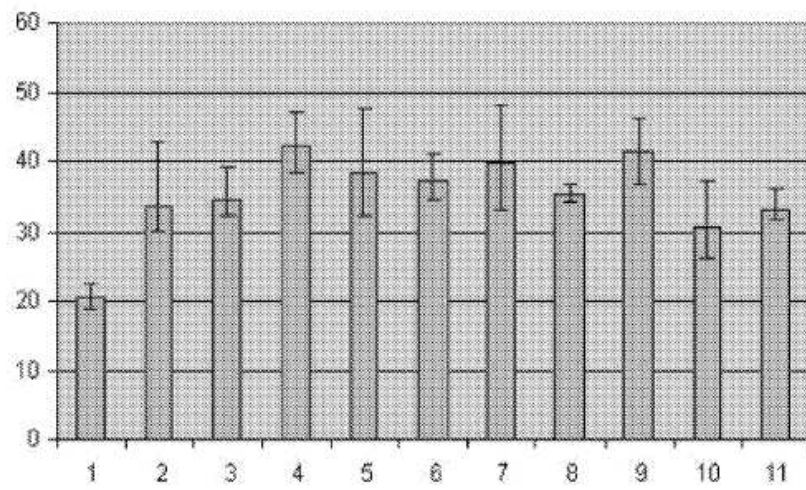


Fig. 9. Averages and Ranges of Values from Table 4.